

In the Claims:

Please cancel claims 7-14 without prejudice, and add new claims 15-16 as

follows:

1. (Original) A texturing apparatus for a recording medium substrate, comprising:

a rotational spindle supported for rotation in an attitude perpendicular to a predetermined datum plane;

a contact member supported for movement in a radial direction of the rotational spindle along the datum plane; and

a drive connected to the rotational spindle so as to vary a rotation rate of the rotational spindle in response to movement of the contact member.

2. (Original) The texturing apparatus according to claim 1, further comprising a vibrator connected to the contact member so as to reciprocate the contact member by a predetermined amplitude along the radial direction.

3. (Original) The texturing apparatus according to claim 2, further comprising an urging force adjuster connected to the contact member so as to maintain an urging force of the contact member constant, said urging force exerted on a substrate for a recording medium mounted on the rotational spindle.

4. (Original) A method of texturing a substrate for a recording medium, comprising:

contacting a contact member against the substrate of a disk-shape rotating around a rotational spindle;

moving the contact member in a radial direction of the substrate; and

varying a rotation rate of the substrate around the rotational spindle in accordance with movement of the contact member.

5. (Original) The method of texturing according to claim 4, further comprising reciprocating the contact member in contact with the substrate by a predetermined amplitude along the radial direction.

6. (Original) The method of texturing according to claim 5, wherein a constant urging force is applied from the contact member to the substrate irrespective of the movement of the contact member.

7-14. (Cancelled)

15. (New) An apparatus designed to texture a substrate of a recording medium, comprising:

a rotational spindle supported for rotation in an attitude perpendicular to a predetermined datum plane, said rotational spindle receiving the substrate;

b2 a contact member supported for movement in a radial direction of the rotational spindle along the datum plane; and

b a drive connected to the rotational spindle so as to vary a rotation rate of the rotational spindle in response to movement of the contact member.

16. (New) The apparatus according to claim 15, wherein said substrate has no magnetic film thereon.

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